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OFFICE OF PETITIONS 503.30414V16

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KATO, et al.

Serial No.: 09/552,572

Filed: April 19, 2000

For: VACUUM PROCESSING APPARATUS AND OPERATING
METHOD THEREFOR

Group: 3749

Examiner: S. Gravini

SUBMISSION UNDER 37 CFR 1.114

Assistant Commissioner for Patents
Washington, D.C. 20231

November 22, 2000

Sir:

Subsequent to granting of the concurrently filed Petition To Withdraw From Issue Based On 37 CFR 1.313(c)(2), and to withdrawal of the above-identified application from issue, and upon granting the concurrently filed Request for Continued Examination, please amend the above-identified application as follows:

IN THE CLAIMS

Please amend the claims presently in the application as follows:

1. (Amended) A method of transferring a substrate, using apparatus comprising:

a cassette table for mounting in air a cassette which receives plural substrates to be subjected to processing or plural substrates which have been subjected to processing;